

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

1756  
PATENT  
JFW

In re application of:

KO et al.

Application No: 09/894,230

Filed: June 27, 2001

For: APPARATUS AND METHOD FOR ARGON  
PLASMA INDUCED ULTRAVIOLET LIGHT  
CURING STEP FOR INCREASING SILICON-  
CONTAINING PHOTORESIST SELECTIVITY



Attorney Docket No: LAM2P257

Examiner: J. Ruggles

Group Art Unit: 1756

Date: July 6, 2004

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on July 6, 2004.

Signed:

Michael L. Gencarella

Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims Remaining After <u>Amendment</u>	Highest Previously <u>Paid For Extra</u>	Present	SMALL ENTITY <u>RATE FEE</u>	OR	LARGE <u>RATE FEE</u>	ENTITY
TOTAL CLAIMS	12 -	36	00	X09 = \$	OR	X18 = \$	
INDEP CLAIMS	02 -	05	00	X42 = \$	OR	X84 = \$	
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$140		X280 = \$	
TOTAL				\$ _____		\$ _____	



Applicant(s) hereby petition for a two-month extension of time to respond to the outstanding Office Action. Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805 (Order No. LAM2P257).



Enclosed is our Check No. 1155 in the amount of \$420.00 to cover the additional claim fee and/or extension of time fees.



If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P257). A copy of this sheet is enclosed.

Respectfully submitted,  
MARTINE & PENILLA, LLP

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Signed: 

Michael L. Gencarella

OFFICE ACTION RESPONSE

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Advisory Action dated February 3, 2004. A two month extension of time is hereby petitioned for, to extend the period of response to July 3, 2004, which falls on a Saturday. As the following Monday, July 5, 2004 is a holiday, the period for response is extended to July 6, 2004. Please consider the following arguments:

A current listing of the claims are provided for the Examiner's convenience which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

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